



Advances in RF MEMS Devices

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Message from the Guest Editor

Radio frequency micro-electro-mechanical (RF MEMS) systems offer unique, low-cost, and exceptional RF performance, unmatched by their pure mechanical or silicon counterparts to many wireless applications. This Special Issue seeks original research presented as review and articles that showcase advances in RF MEMS devices, their applications, actuation mechanisms, and novel fabrication techniques. We are interested in RF MEMS technologies that enable distinct advantages in:

- i. high-performance high-power tunable microwave filters;
- ii. frequency-tunable and radiation pattern reconfigurable and steerable antennas;
- iii. frequency-selective surfaces;
- iv. impedance matching networks for extensive impedance coverage over wide frequency ranges;
- v. phase shifters with small phase-shift values and broadband frequency coverage;
- and vi. switching networks that offer low-loss ultra-wide bandwidth operation.





Editor-in-Chief

Message from the Editor-in-Chief

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